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CROWELL & MORING, LLP
Intellectual Property Group
P.O. Box 14300
Washington, D.C. 20044-4300
202) 624-2500

October 3, 2003

Customer No.

23911

Mail Stop PATENT APPLICATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Re: New U.S. Patent Appln.
Our Ref: 010986.52822US

Sir:

Transmitted herewith for filing is the patent application of:

Hiroshi SHINRIKI and Shintaro AOYAMA

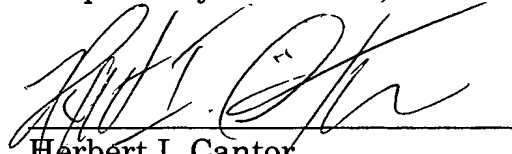
entitled: **Method of and Apparatus for Processing Substrates**

Enclosed are:

1. Specification, including 14 claims (pages 16), in Japanese.
2. 8 Sheets of drawings showing Figs. 1-8.
3. Application Data Sheet
4. Priority is being claimed under 35 U.S.C. §119 and 37 C.F.R. §1.55 based on Priority Document 2002-291579, filed in Japan on October 3, 2002.

The filing fee is being deferred.

Respectfully submitted,



Herbert I. Cantor
Reg. No. 24,392

HIC:tcv

22387 U.S. PTO
10/678045
10/03/03

